

Docket No.: M4065.0466/P466

(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Neal Rueger

Application No.: 09/938,644

Confirmation No.:

Filed: August 27, 2001

Art Unit: 1765

For:

METHOD AND APPARATUS FOR MICROMACHINING USING A

MAGNETIC FIELD AND PLASMA

ETCHING

Examiner: T. Mackey

INFORMATION DISCLOSURE STATEMENT (IDS)

MS RCE Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO/SB/08. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

In accordance with 37 C.F.R. § 1.97(g), the filing of this Information Disclosure Statement shall not be construed to mean that a search has been made or that no other material information as defined in 37 C.F.R. § 1.56(a) exists. In accordance with 37 C.F.R. § 1.97(h), the filing of this Information Disclosure statement shall not be construed to be an admission that any patent, publication or other information referred to therein is "prior art" for this invention unless specifically designated as such.

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It is submitted that the Information Disclosure Statement is in compliance with 37 C.F.R. §1.98 and the Examiner is respectfully requested to consider the listed references.

The Director is hereby authorized to charge any deficiency in the fees filed, asserted to be filed or which should have been filed herewith (or with any paper hereafter filed in this application by this firm) to our Deposit Account No. 04-1073, under Order No. M4065.0466/P466. A duplicate copy of this paper is enclosed.

Dated: March 2, 2004

Respectfully submitted,

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PTO/SB/08a/b (08-03)
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Complete if Known Substitute for form 1449A/B/PTO Application Number 09/938,644-Conf. #1172 INFORMATION DISCLOSURE August 27, 2001 Filing Date STATEMENT BY APPLICANT **Neal Rueger** First Named Inventor Art Unit 1765 (Use as many sheets as necessary) T. Mackey **Examiner Name** Sheet 1 . of 2 Attorney Docket Number M4065.0466/P466

	U.S. PATENT DOCUMENTS				
Examiner	Cite No.1	Document Number	Publication Date	Name of Patentee or	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
Initials*		Number-Kind Code ² (if known)		Applicant of Cited Document	
	Α	5,976,347	11/1999	Wakabayashi et al.	
	В	6,103,399	8/2000	Smela et al.	
	С	5,972,193	10/1999	Chou et al.	

FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No.1	Foreign Patent Document Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	

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		NON PATENT LITERATURE DOCUMENTS	
Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	C1	MARC SCHAEPKENS et al.; "Asymmetric microtrenching during inductively coupled plasma oxide etching n the presence of a weak magnetic field", Applied Physics Letters, Vol. 72, Number 11, March 16, 1998.	
	C2	K. DONOHOE; "Aspect Ratio-Plasma Effects" March 14, 2000.	
	C3	"Introduction to Microengineering, Mask Design", http://www.dbanks.demon.co.uk/ueng/maskdes.html_accessed_July 3, 2001.	
	C4	"Introduction to Microengineering, LIGA", http://www.dbanks.demon.co.uk/ueng/liga.html accessed July 3, 2001.	
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	C6	"Introduction to Microengineering, Wafer bonding", http://www.dbanks.demon.co.uk/ueng/waferbond.html_accessed July 3, 2001.	
	C7	"Introduction to Microengineering, Electrochemical etching of silicon", http://www.dbanks.demon.co.uk/ueng/electrochem.html accessed July 3, 2001.	
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Substitute for form 1449A/B/PTO				Complete if Known		
				Application Number	09/938,644-Conf. #1172	
1	NFORMATION	N DIS	SCLOSURE	Filing Date	August 27, 2001	
9	STATEMENT BY APPLICANT			First Named Inventor	Neal Rueger	
				Art Unit	1765	
	(Use as many sheets as necessary)			Examiner Name	T. Mackey	
Sheet	2	of	2	Attorney Docket Number	M4065.0466/P466	

C14	"Introduction to Microengineering, Basic techniques", http://www.dbanks.demon.co.uk/ueng/sitech.html_accessed_July 3, 2001.	
C15	"Integrated MicroElectroMechanical Systems", http://www.mdl.sandia.gov/micromachine/integrated.html accessed July 3, 2001.	
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C17	"MEMS Overview", http://www.mdl.sandia.gov/micromachine/overview.html accessed July 3, 2001.	
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C19	PHILIP BALL; "Honey, I shrunk the cogs", http://www.nature.com/nsu/010111/010111-3.html July 12, 2001.	

Examiner	Date
Signature	Considered

^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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